



501.30598CC3

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s):

MORIOKA, et al

Serial No.:

09/805,188

Filed:

March 14, 2001

For:

METHOD AND APPARATUS FOR ANALYZING THE STATE

OF GENERATION OF FOREIGN PARTICLES IN SEMICONDUCTOR FABRICATION PROCESS

Group:

2877

Examiner:

T. Nguyen

## <u>AMENDMENT</u>

Mail Stop Amendment Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

June 28, 2004

Sir:

In response to the Office Action March 26, 2004, the following amendments and remarks are respectfully submitted in connection with the above-identified application, as listed below and as set forth on the following pages:

Amendment of the Claims; and

Remarks are included following the amendments.